

# Addressing Edge Recombination Losses in Shingle Cells by Holistic Optimization of the Process Sequence

A. Göbel<sup>1,2</sup>, E. Lohmüller<sup>1</sup>, D. Wagenmann<sup>1</sup>, N. Kohn<sup>1</sup>, M. Hofmann<sup>1</sup>, J.D. Huyeng<sup>1</sup>, R. Preu<sup>1,2</sup>  
<sup>1</sup>Fraunhofer Institute for Solar Energy Systems ISE, Heidenhofstr. 2, 79110 Freiburg, Germany  
<sup>2</sup>University of Freiburg, INATECH, Emmy-Noether-Str. 2, 79110 Freiburg, Germany  
 Corresponding author: alexander.goebel@ise.fraunhofer.de

## Cutting-Induced Edge Recombination

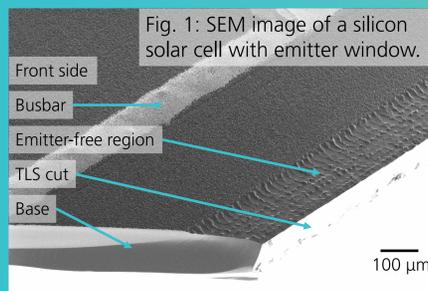
- Shingle solar cells: cut full host cells into sub cells
  - Cut edges: increased recombination rate<sup>[1]</sup>  $R_{surf} = v_{th}(n_s p_s - n_{i,eff}^2) \int_{E_v}^{E_c} \frac{D_{it}(E) dE}{\frac{n_s + n_1(E)}{\sigma_p(E)} + \frac{p_s + p_1(E)}{\sigma_s(E)}}$
- Reduce  $R_{surf}$  by:
  - Lowering conductivity near the edge (emitter window)<sup>[2,3]</sup>
  - Implementing a field barrier for  $n_s$  or  $p_s$  (field effect passivation, PET)<sup>[4,5]</sup>
  - Reducing defect quantity  $D_{it}$  at the edge (chemical passivation, PET)<sup>[4,5]</sup>

## Conclusion

- Application of laser ablation of emitter windows
  - Proof of concept for edge passivation behavior
- Improvement of passivated edge technology (PET)
  - Effect on lifetime sample: +75 %
  - Recovery of cutting losses increased by 24 %
  - Up to 80 % recovery achieved

## Option 1: Remove Emitter

### Suppress Current Flow Towards Cut Edge

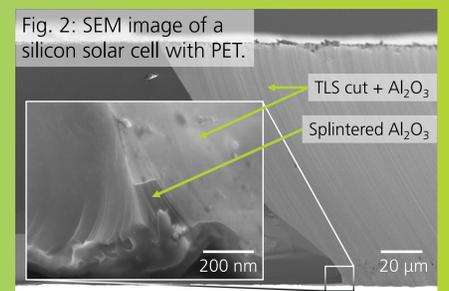


## Experimental Approaches

Option 1	Option 2
As-cut wafer	As-cut wafer
Texture & diffusion	Texture & diffusion
Laser doped selective emitter (optional)	Laser doped selective emitter (optional)
<b>Laser ablation</b>	<b>Laser ablation</b>
Removal rear emitter	Removal rear emitter
Passivation and ARC	Passivation and ARC
Laser contact opening (LCO)	Laser contact opening (LCO)
Screen printing	Screen printing
Contact formation	Contact formation
Cell separation	Cell separation
	<b>PET: ALD + annealing</b>

## Option 2: Dielectrics

### Field Effect and Chemical Passivation



## Emitter Window<sup>[3]</sup>

- Laser ablation process
  - Symmetric lifetime samples
  - Ablation on front, rear or both sides
  - Evaluation after passivation
- Ablated regions with increased lifetime
  - Laser process variation reveals little effect (not shown here)

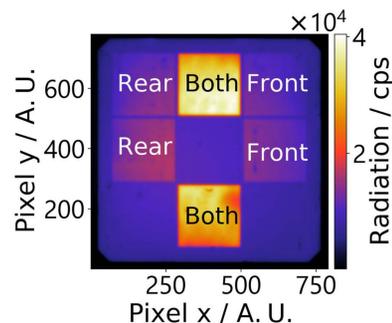


Fig. 3: The photoluminescence of the lifetime sample shows the removed emitter.

- QSSPC measurement
  - Different positions
  - Applied constant  $f_{abs}$
- Lifetime in ablated regions increased
  - Differences due to changed optics of lasered surface
- Ablation removes emitter

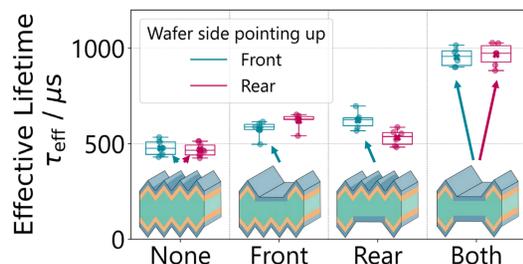


Fig. 4: The effective lifetime  $\tau_{eff}$  is measured from both sides for each field from Fig. 3.

## Emitter Windows on Shingle Cells

- Comparison of PERC shingle cells with and without emitter window
  - Advantage in  $pFF$ :  $\frac{\Delta pFF(\text{Host - Shingle})_{\text{with window}}}{\Delta pFF(\text{Host - Shingle})_{\text{without window}}} = 17 \%$
- Challenges
  - $J_{sc}$  loss 0.24 mA/cm<sup>2</sup>: optics + less emitter area
  - Alignment: metal + cutting



Fig. 5: Two shingle cells side by side with the emitter window after cutting using thermal laser separation (TLS).

## Passivated Edge Technology (PET)<sup>[4]</sup>

- FZ-Si lifetime samples and cut shingle cells
- Coating  $Al_2O_3$ : plasma enhanced atomic layer deposition (PE-ALD)<sup>[6]</sup>
- Annealing: batch oven
- Characterization
  - $\tau_{eff}$  by QSSPC
  - $I-V$  by cell tester



Fig. 6: FZ-Si wafer

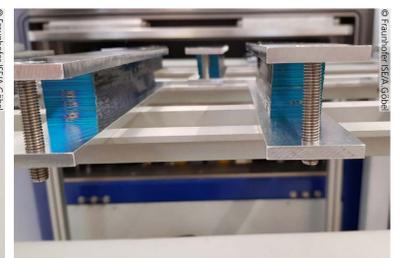


Fig. 7: Stacked shingle cells before running the high throughput ALD reactor.

- Variation of ALD process
  - PE-ALD layers require anneal for high lifetimes
- Reference process<sup>[4]</sup>:  $\tau_{eff} = 2.1$  ms
- Adjusted process (same cycle time):  $\tau_{eff} = 3.8$  ms (+ 75 %)

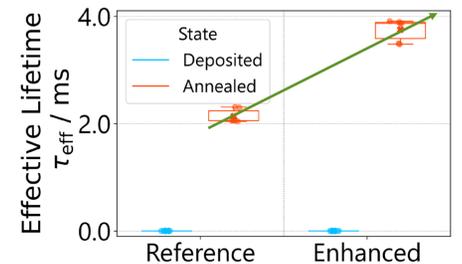


Fig. 8: The effective lifetime  $\tau_{eff}$  is strongly increased with an enhanced ALD process.

## Effect of Improved ALD Process on Cells

- Cells cut by thermal laser separation (TLS)
- Gain of PET improved by 24 %
- Relative improvement less than on lifetime samples
- PET achieves recovery of up to 80 %

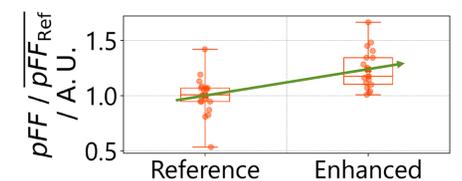


Fig. 9: The enhanced ALD process increases the  $pFF$  recovery on cut silicon solar cells.

1 A. Richter, PhD Thesis, Universität Konstanz, 2014.  
 2 S. W. Glunz, et al., IEEE, 2002, DOI: 10.1109/PVSC.2002.1190556  
 3 E. Lohmüller, et al., Patent, 2018, DE 10 2018 123 484  
 4 E. Lohmüller, et al., Patent, 2018, DE 10 2018 123 485  
 5 P. Balozian, et al., IEEE, 2020, DOI: 10.1109/PHOTOV.2019.2959946  
 6 E. Lohmüller, et al., Sol. Energy Mater., 2023, DOI: 10.1016/j.solmat.2023.112419



Fraunhofer ISE contributions  
 41st EU PVSEC  
 ise.link/  
 eupvsec2024

The authors would like to thank all involved colleagues for their support. The activities have been financially supported by:  
 German Federal Ministry for Economic Affairs and Climate Action within the research projects "GutenMorgen" (FKZ 03EE1101A) and "Liebesbrief" (FKZ 03EE1151A)  
 Stiftung Nagelschneider within a PhD scholarship for Alexander Göbel

